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## Modeling of nanoscale gallium nitride (GaN) HFET with gate field-plated heterostructure

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The excellent microwave power performance demonstrated in AlGa<sub>N</sub>/Ga<sub>N</sub> HEMTs (high-electron mobility transistors) results from the combination of high current density with high voltage operation [1], which benefits from the high sheet charge density in these heterostructures ( $10^{13} \text{ cm}^{-2}$ ), the high carrier mobility ( $1500 \text{ cm}^2/\text{Vs}$ ) and saturation velocity ( $1.5 \times 10^7 \text{ cm/s}$ ) in the channel and the high breakdown voltage inherent in the Ga<sub>N</sub> material. However, their reliability still limits their applications in today's electronic systems. The newly developed Gate Field-Plated AlGa<sub>N</sub>/Ga<sub>N</sub> high electron mobility transistors

show improved performance due to the electric field reduction in the device channel and surface modification [2, 3]. We report on two dimensional numerical simulations of Gate-Recessed and Field-Plated AlGa<sub>N</sub>/Ga<sub>N</sub> HFETs where all the important device parameters have been defined, the insulator thickness and permittivity under the Gate Field-Plated is also an important design parameter to attain higher breakdown voltage, thus an improvement of the performances of HFETs

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